

Abstract of the Disclosure

COATING TREATMENT APPARATUS, COATING AND DEVELOPING
TREATMENT SYSTEM, COATING TREATMENT METHOD, AND
RECORDING MEDIUM HAVING PROGRAM RECORDED THEREON
FOR EXECUTING COATING TREATMENT METHOD

A coating treatment apparatus supplying a coating solution to a front surface of a rotated substrate and diffusing the supplied coating solution to an outer periphery side of the substrate to thereby apply the coating solution on the front surface of the substrate includes: a substrate holding part holding a substrate; a rotation part rotating the substrate held on the substrate holding part; a supply part supplying a coating solution to a front surface of the substrate held on the substrate holding part; and an airflow control plate provided at a predetermined position above the substrate held on the substrate holding part for locally changing an airflow above the substrate rotated by the rotation part at an arbitrary position.

FIG. 5